

Appl. No. 10/823,078
Reply to Office Action of March 22, 2007
Amendment dated: July 23, 2007

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claim 1. (Canceled)

2. (Currently Amended) An electrolytic polishing apparatus for electrolytic-polishing a conductive film formed on a substrate, comprising:

a resistance measuring unit for measuring electric resistance of said conductive film and a any etching stopper film formed on said substrate, and further comprising a termination point detecting unit for detecting a termination point of polishing by reading a variation resistance value of said conductive film and said etching stopper film measured by said resistance measuring unit, wherein said resistance measuring unit measures an indication of the electrical resistance across the substrate at a plurality of locations around the periphery of the substrate.

Claims 3.-10. (Canceled)